

High Sensitivity Magnetic Sensors for Biotechnology

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Interfacing Concepts**

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Outline

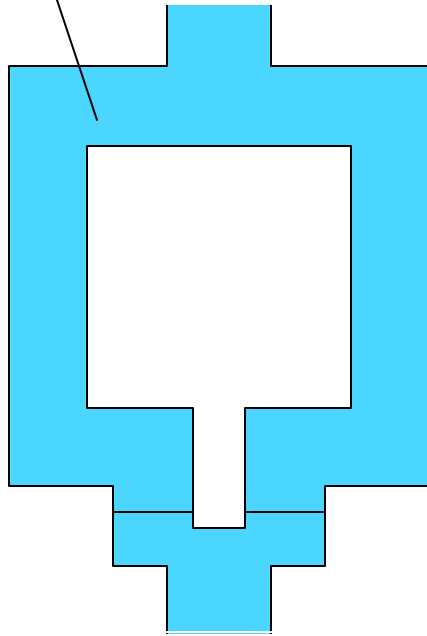
- Magnetic fields in biotechnology
 - Very brief introduction
 - Scanning techniques
- Magnetic fields associated with small magnetic particles (MPs)
 - Characteristics
 - Material
 - Moment
 - B fields
- Integrated magnetic field sensors
 - Spin valves
 - Magnetic tunnel junctions
 - Hall devices
- Summary

Magnetic fields in biotechnology

- A long history ...
 - E.g. Magnetoencephalography
- ... and a wide variety
- This talk will focus on magnetic fields that are localized on a small spatial scale
- Such fields could be associated with magnetotactic bacteria
- Or they could be generated by small magnetic particles (MPs) used to “tag” a biological or chemical agent

Scanning techniques

SQUID loop



$\sim 10 \mu\text{m}$

Room temperature

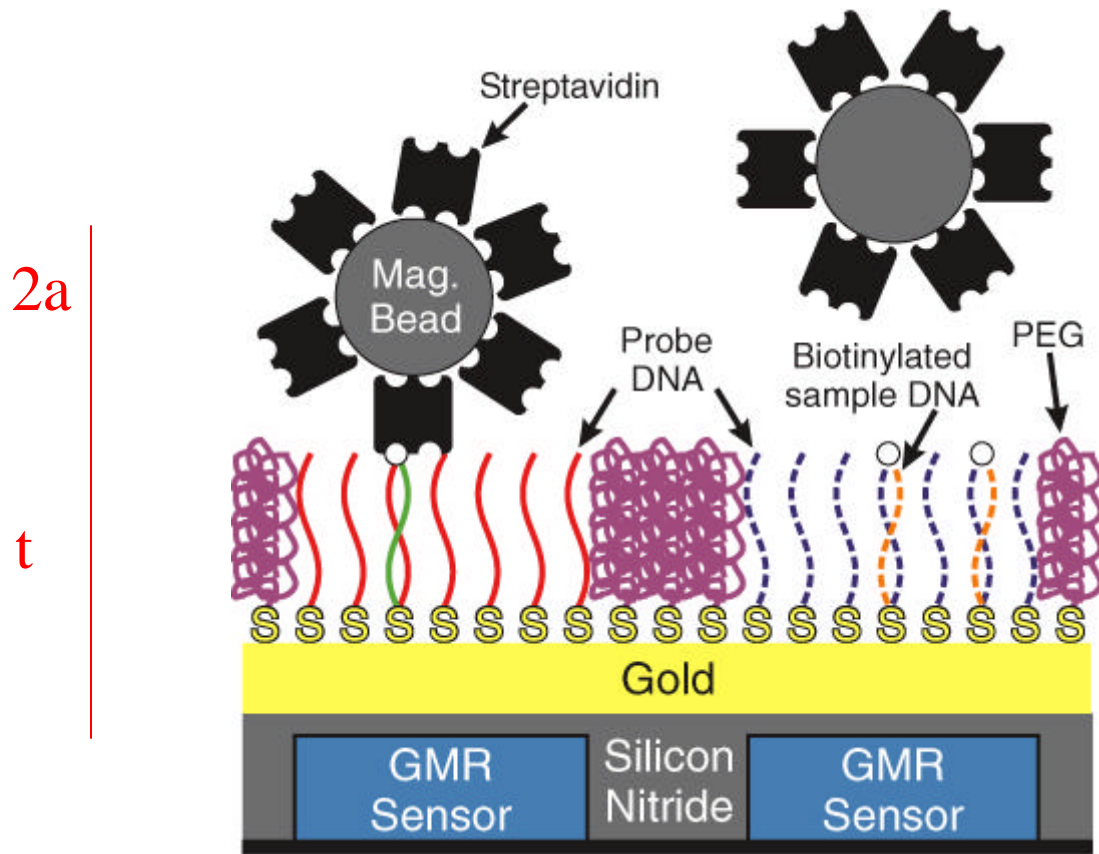
$20 \mu\text{m}$

vacuum

Cold finger

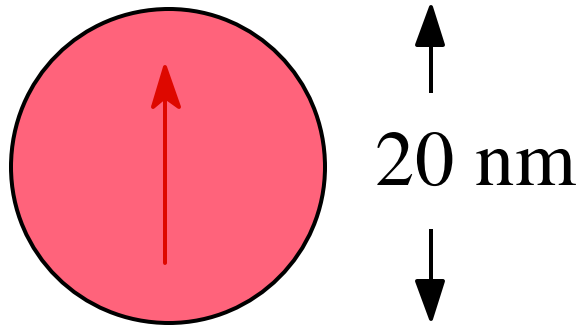
- Scanning (or fixed) SQUIDs
- Cryogenic sensors
- Lateral resolution limited by vertical separation
- Very high field sensitivity
- Study motion of magnetotactic bacteria (mostly ensembles, some claims of single bacterium)
- Fred Wellstood (U. Md.)
- John Clarke (UC Berkeley)
 - Biophys. J. v. 76, 3323 (99)
- Also: Magnetic force microscopes (MFM)

Detecting magnetic beads with integrated (on-chip) sensors

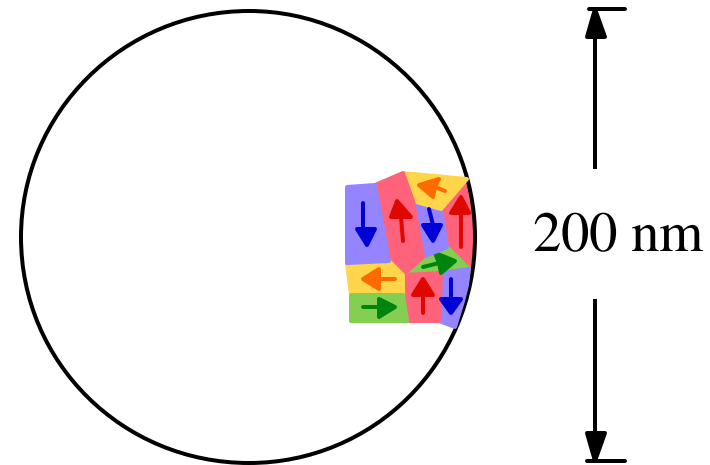


- NOT TO SCALE
- In this example, bead gets stuck to surface of chip by some chemical recognition process of interest

Magnetic nanoparticles (beads)



- Single domain particle (SDP), e.g. Fe, Ni, NiFe
- High remanence (always has a moment)
- Tendency to clump
- $\mathbf{m} = (4\pi/3)a^3 \mathbf{M}$
- $\mathbf{M} = 1700 \text{ emu/cm}^3$ (Fe)
- $\mathbf{m} = 7 \times 10^{-15} \text{ emu}$ (Fe, $a=10 \text{ nm}$)



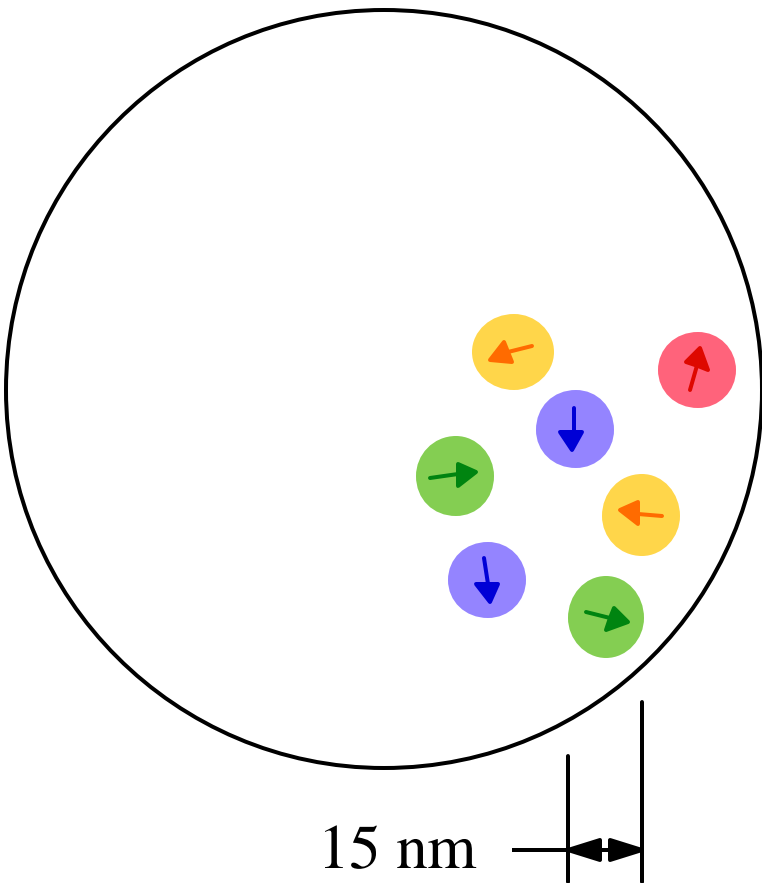
- “Soft” ferromagnetic material (Fe, Py, Ni, etc.)
- Zero remanence (NO net moment in zero field)
- Avoid clumping

Moment \propto applied field:

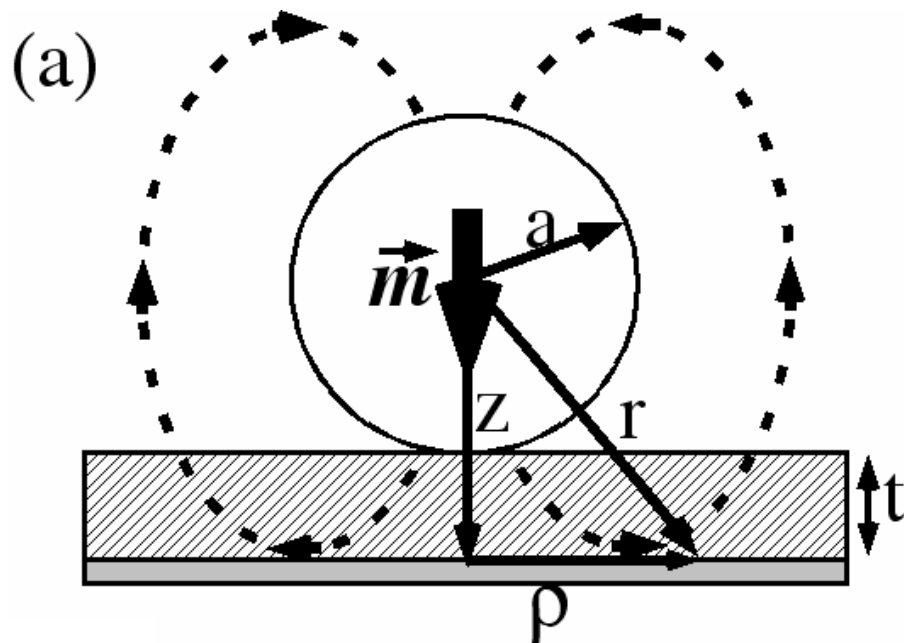
$$\mathbf{M}(\mathbf{H}) = \frac{3}{4\pi} [(\mu-1)/\mu+2] \mathbf{H}$$

$$= \frac{3}{4\pi} \mathbf{H}$$

Magnetic microparticles



- Dynabeads (Dyna)
- Polymer matrix with embedded $\gamma\text{-Fe}_2\text{O}_3$ particles, typ. 6 to 12% vol. fraction
- Commercially available
 - Monodispersed ($2.8 \pm 0.2 \mu\text{m}$)
 - Functionalized, or prepared surface
- Zero remanence (NO net moment in zero field)
- Moment \propto applied field:
 $M(H) \sim (0.1) (3/4\pi)H$
 $M(\text{sat}) = 10 \text{ emu/cm}^3$
 $m = 2 \times 10^{-11} \text{ emu (at } H=100 \text{ Oe, near sat'n; } a = 1.4 \mu\text{m)}$



Magnetic dipole fields generated by MPs

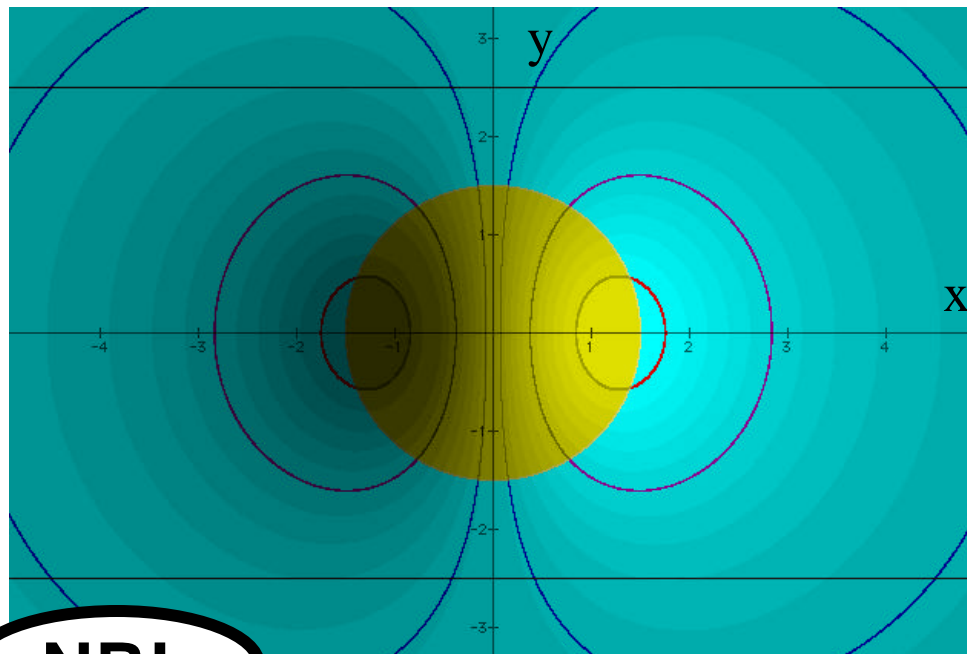
In Cartesian coordinates:

$$B_X = 3m(xz)/r^5$$

$$B_Y = 3m(yz)/r^5$$

$$B_Z = m(3z^2 - r^2)/r^5$$

$$= 2m/r^3 \text{ along } z=0$$



For $a = 10$ nm Fe **SDP**:

$$B_Z = 12,000 \text{ Oe} \quad t \sim 0$$

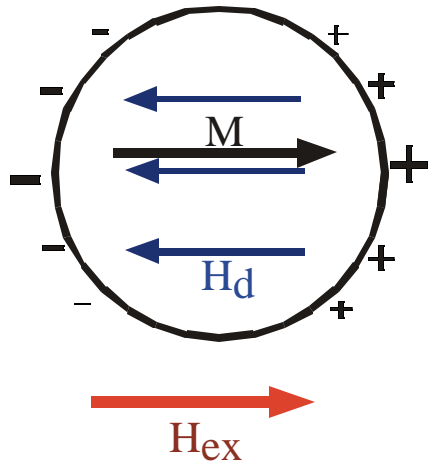
$$B_Z = 65 \text{ Oe} \quad t = 50 \text{ nm}$$

$$B_Z = 10 \text{ Oe} \quad t = 100 \text{ nm}$$

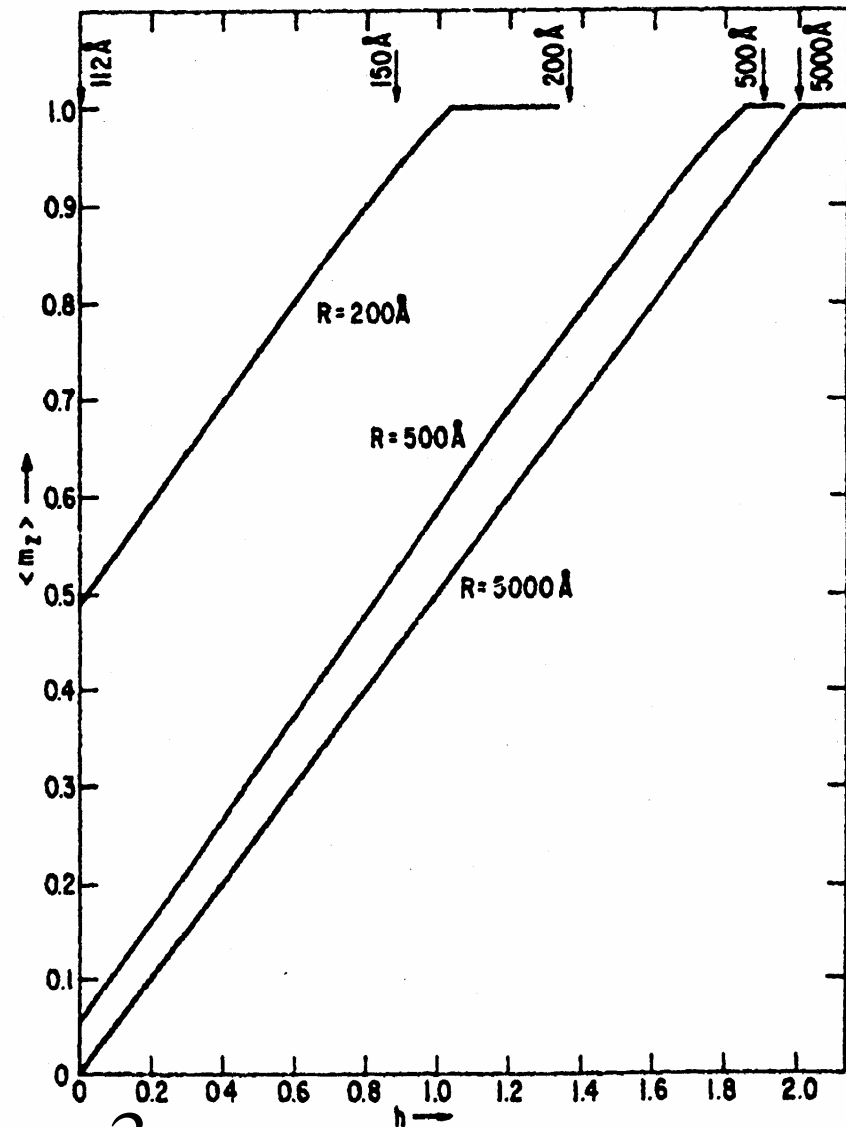
$$B_Z = 1.5 \text{ Oe} \quad t = 200 \text{ nm}$$

What about bigger ferromagnetic spheres

Above $a = 100$ nm, any sphere of (low anisotropy) soft magnetic material will be an effective paramagnet



$$M_{eff} = \frac{M_{int}}{(H_A + \frac{4p}{3} M_{int})} H_{ex}$$

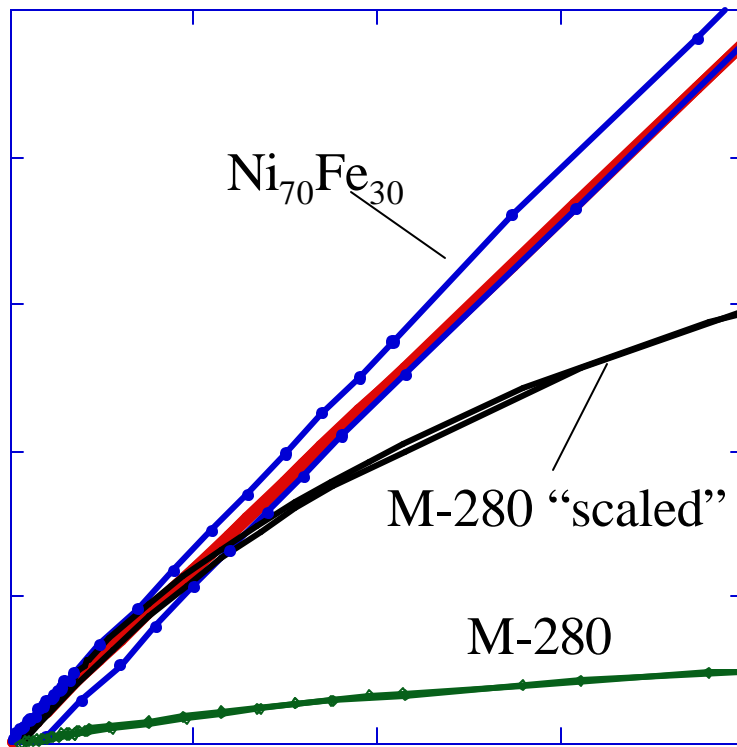


$$\frac{3}{4p} H_{ext}$$

A. Aharoni, *J. Appl. Phys.*
5, 993(1981)

Permalloy MPs: Moments and Fields

Low Field regime



For $a = 100$ nm and $H=100$ Oe:
 $\mathbf{m} = 1 \times 10^{-13}$ emu

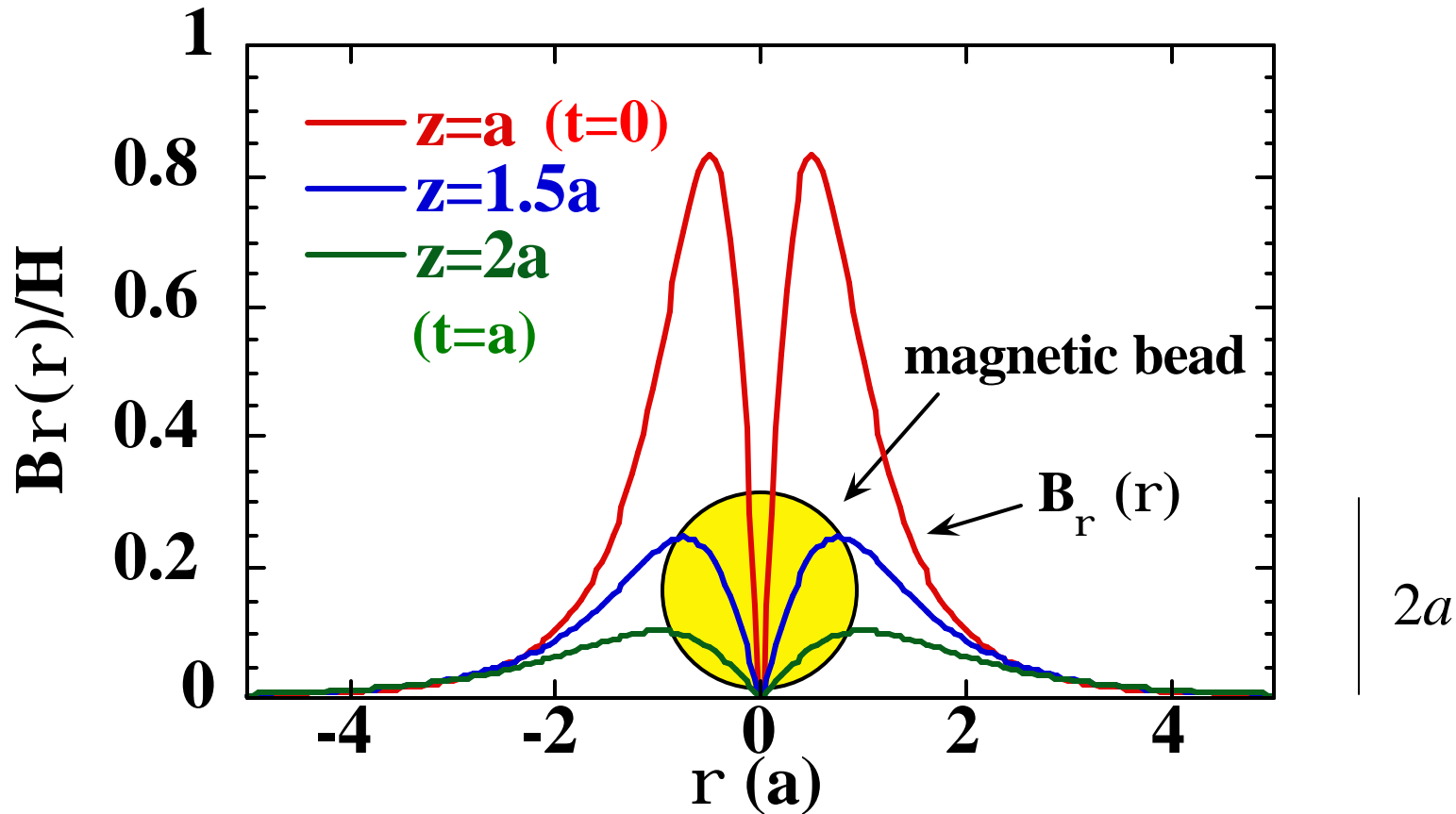
$B_Z = 200$ Oe	$t=0$
$B_Z = 60$ Oe	$t=50$ nm
$B_Z = 25$ Oe	$t=100$ nm
$B_Z = 7$ Oe	$t=200$ nm

For a **Dynal** bead, $H = 100$ Oe:
 $\mathbf{m} = 6 \times 10^{-11}$ emu

$B_Z = 33$ Oe	$t=0$
$B_Z = 27$ Oe	$t=100$ nm

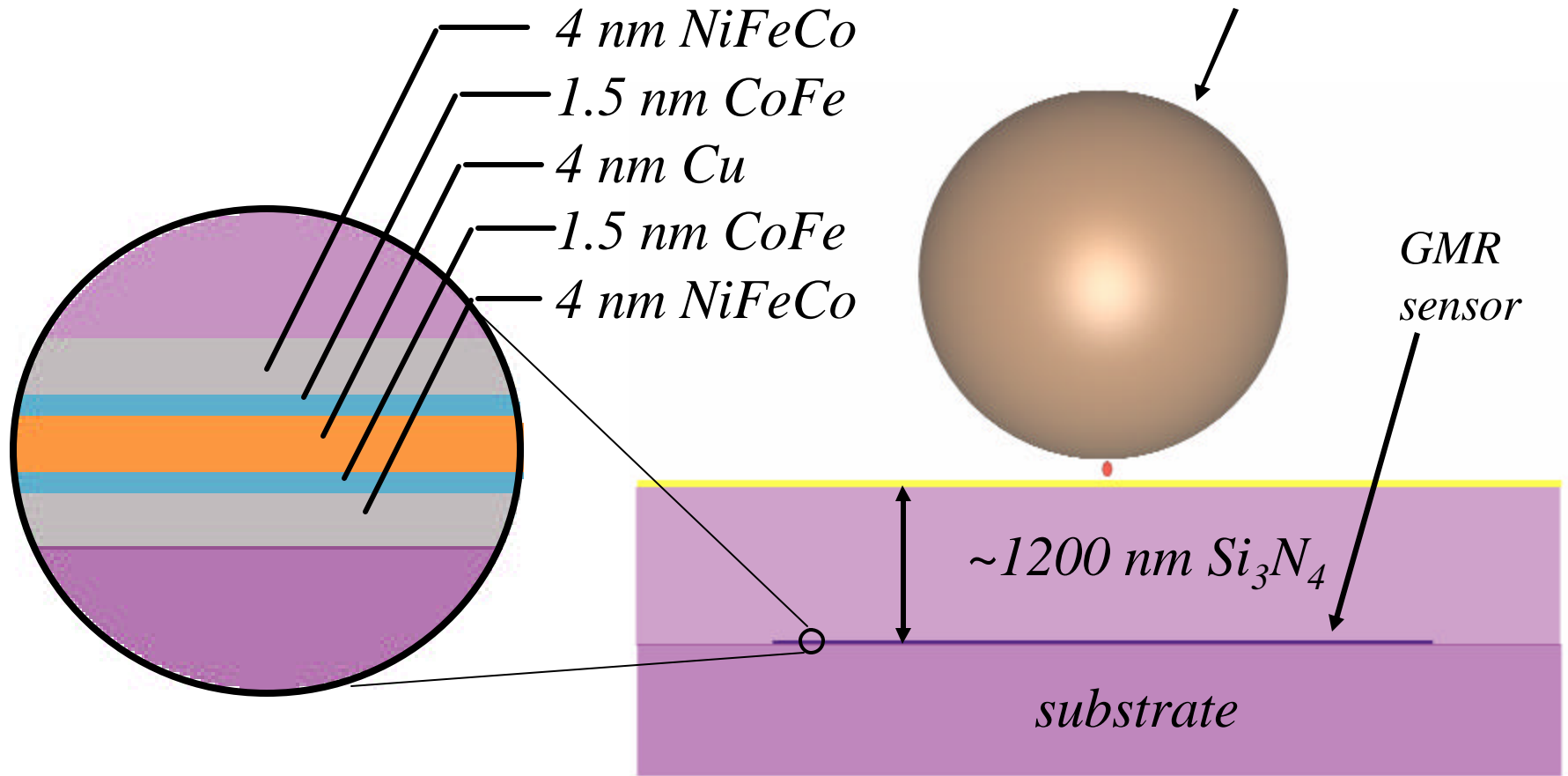
Transverse fields, Py (radial, ρ)

Compare: $B_z = 2$



Typically: work with $H = 100$ Oe, so multiply left axis by 100 to get radial field in Oe. **Detector needs to be right under MP!**

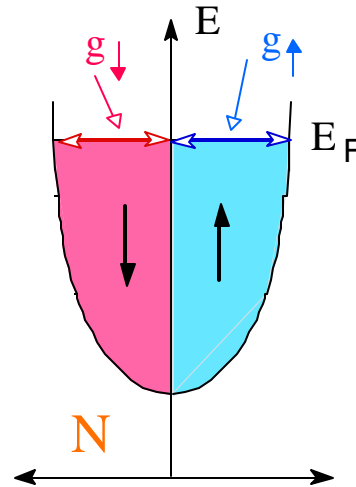
Why care about radial field?
Because that may be relevant to
your sensor



BARC II GMR sensor structure--to scale

Transport properties of metals

Nonmagnetic metals:
e.g. Cu, Au, Ag, Al
R is a few $\mu\Omega\text{-cm}$



$$g \propto N(E)$$

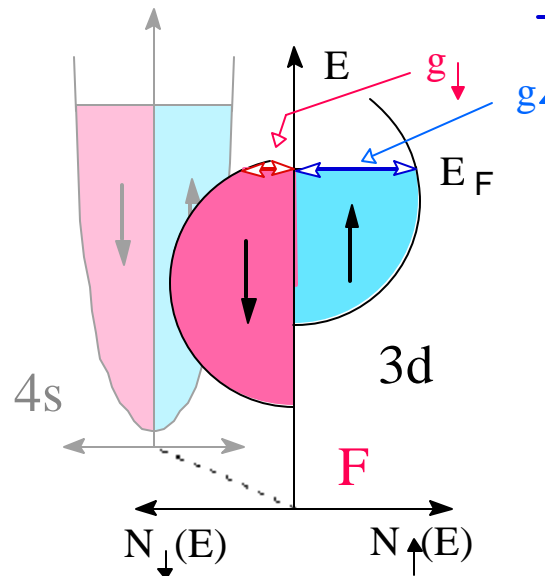
g_{\downarrow} and g_{\uparrow}

don't mix
(orthogonal)

$$g = g_{\downarrow} + g_{\uparrow}$$

$$g_{\downarrow} = g_{\uparrow}$$

Transition
metal **F**erro-
magnets, e.g.
Ni, Fe, Co, NiFe
R is 10s $\mu\Omega\text{-cm}$



$$g_{\downarrow} \neq g_{\uparrow}$$

$$P = \frac{J_{\uparrow} - J_{\downarrow}}{J_{\uparrow} + J_{\downarrow}}$$

$$= \frac{g_{\uparrow} - g_{\downarrow}}{g_{\uparrow} + g_{\downarrow}}$$

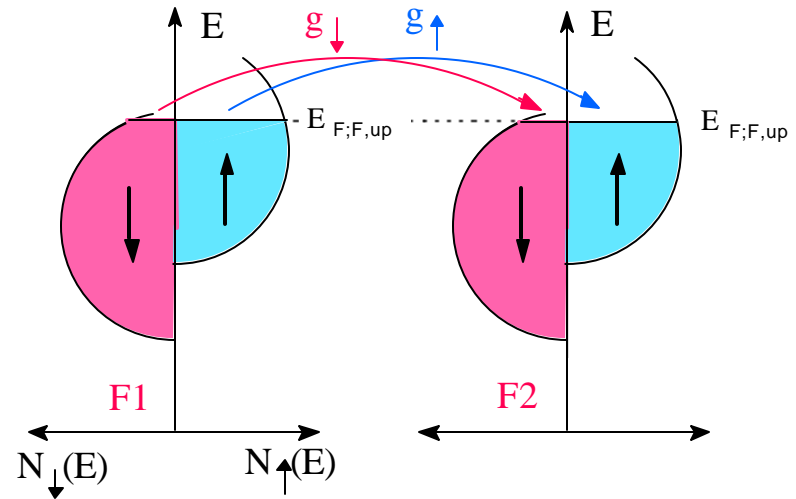
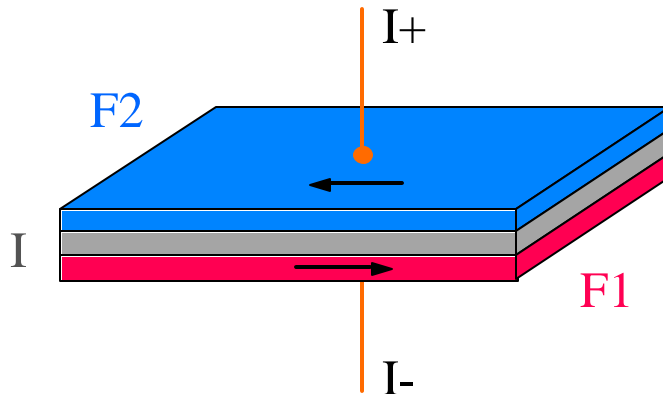
Tunnel MagnetoResistance (TMR) - (aka MTJ)

$$g \propto N(E)_F$$

F1 and F2 **parallel** :

$g_{\uparrow} > g_{\downarrow}$
 g_{\uparrow} dominates

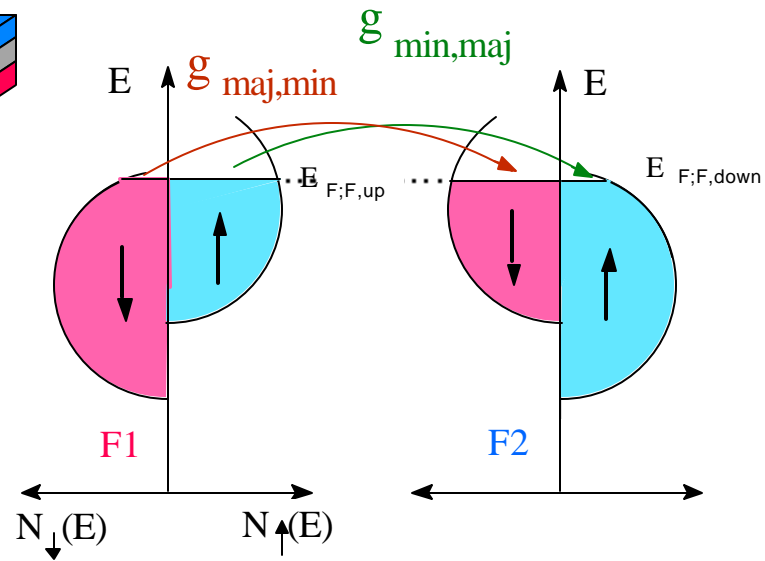
Low R state



F1 and F2 **antiparallel** :

$g_{\min, \text{maj}} = g_{\text{maj}, \min} < g_{\uparrow}$

High R state

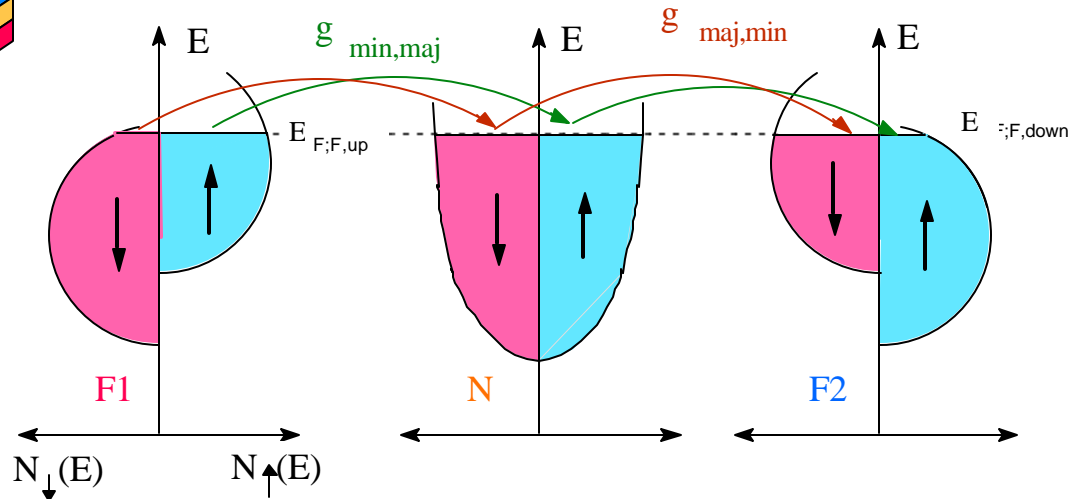
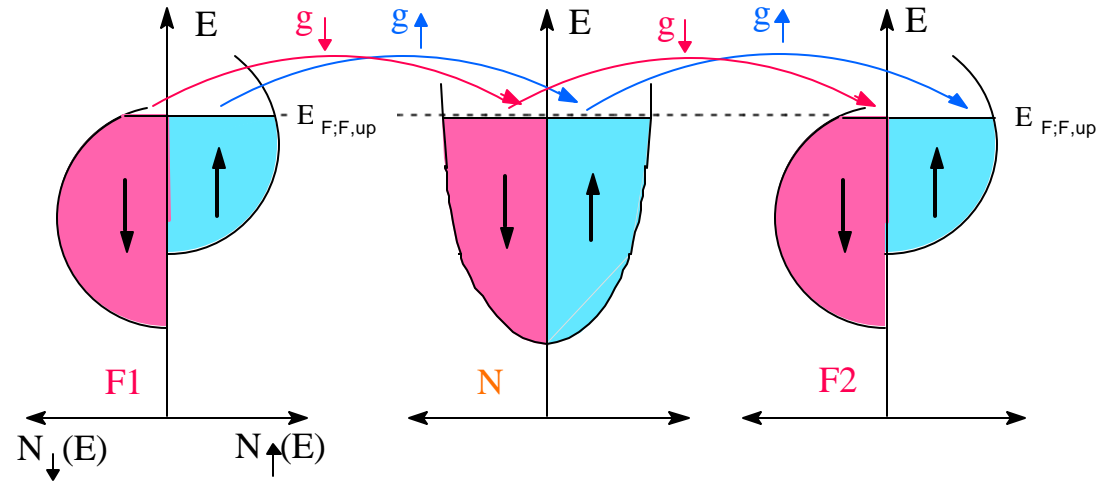
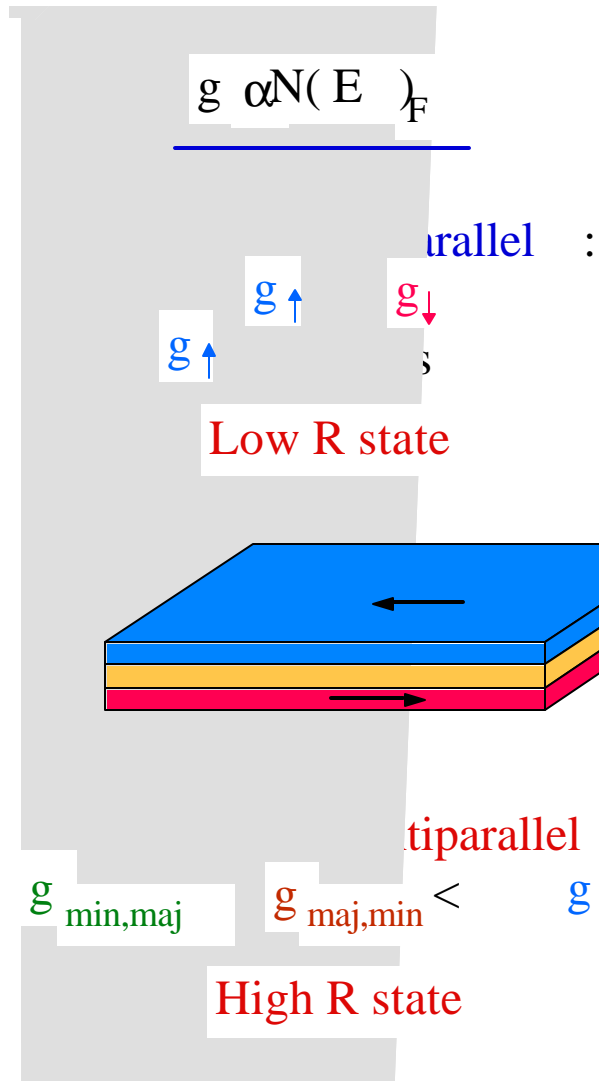


Juliere (1975); Moodera

et al (1995)

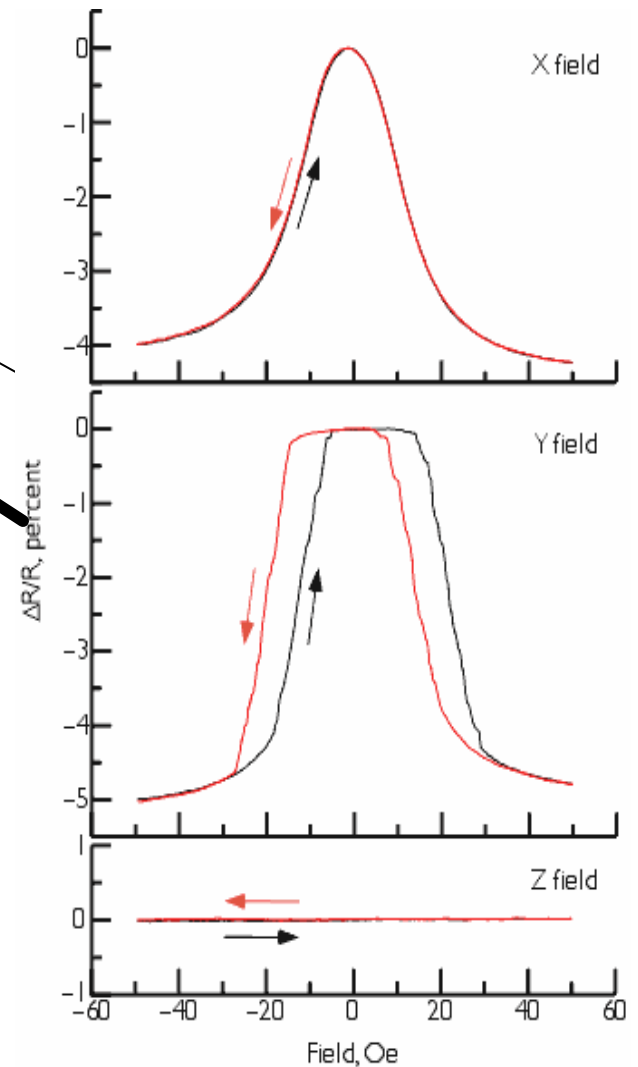
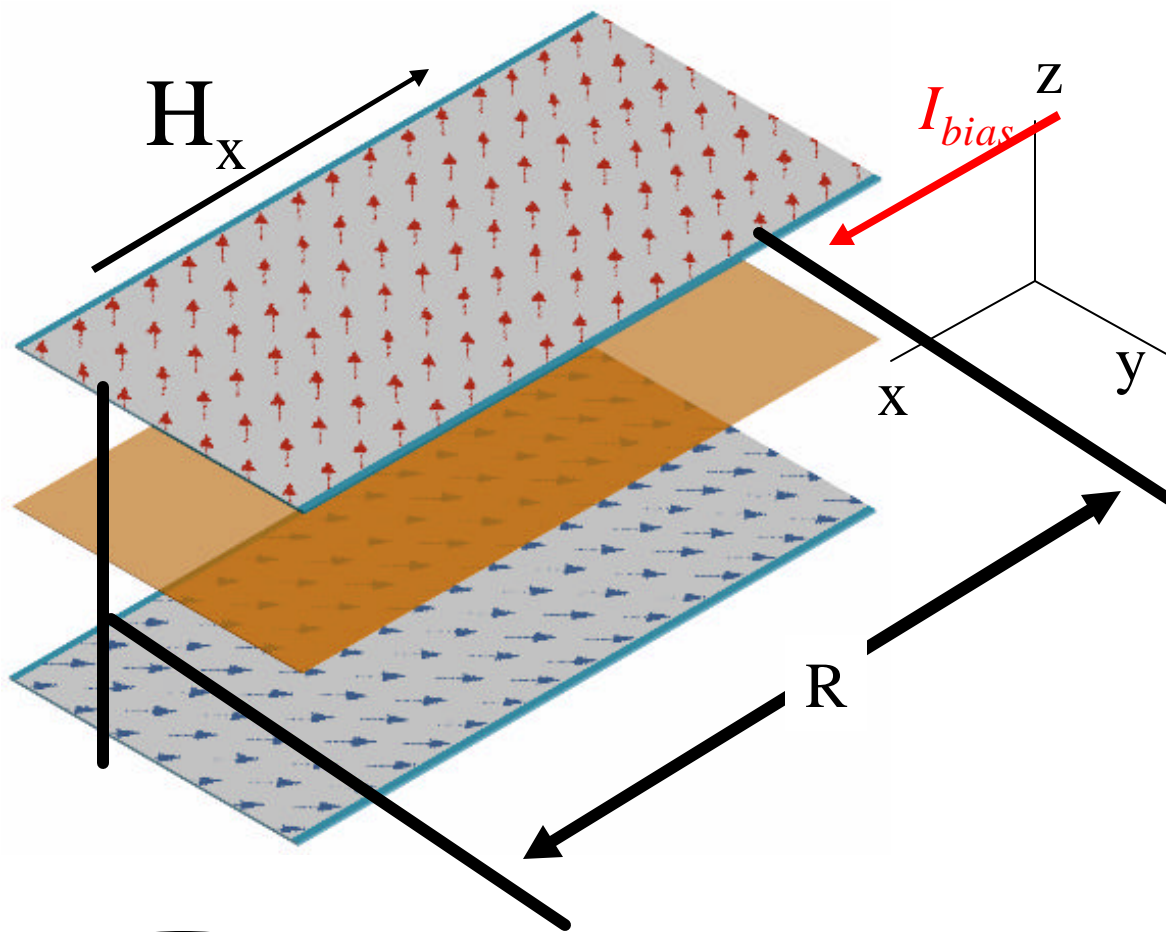
Assumption: NO spin flip during tunneling

Magnetoresistance - spin valve



Grunberg PRB (89), Fe/Cr spin valve MR=1.5%
 Baibich et al., PRL (88), Fe/Cr multilayer

GMR Magnetic Field Sensor Scissors Mode: Uniaxial sensitivity

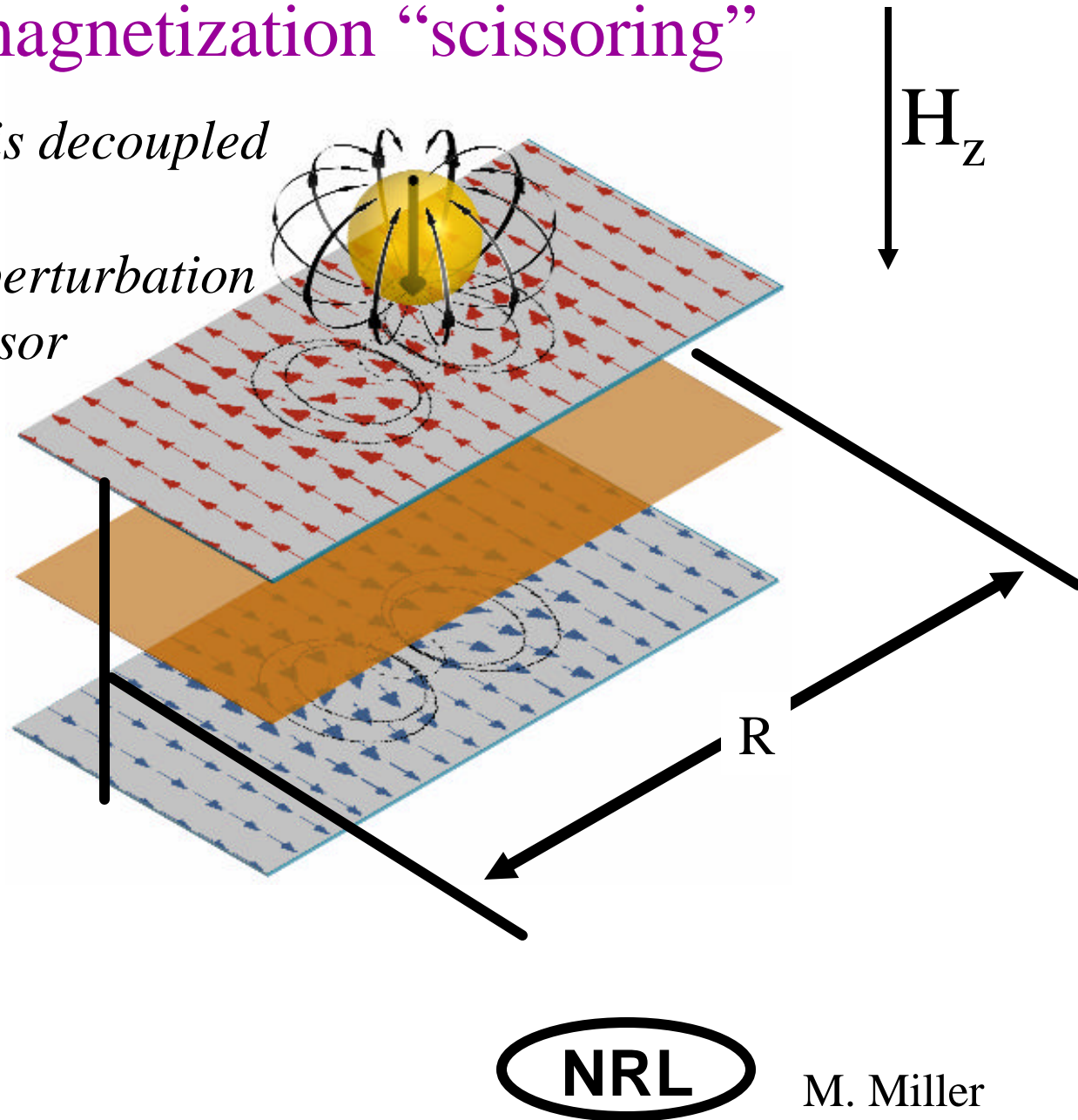
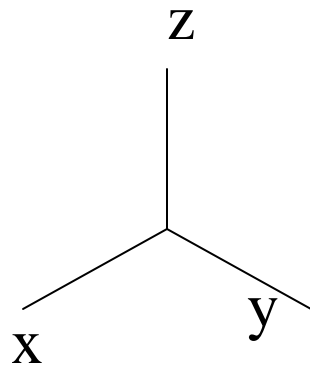


NRL

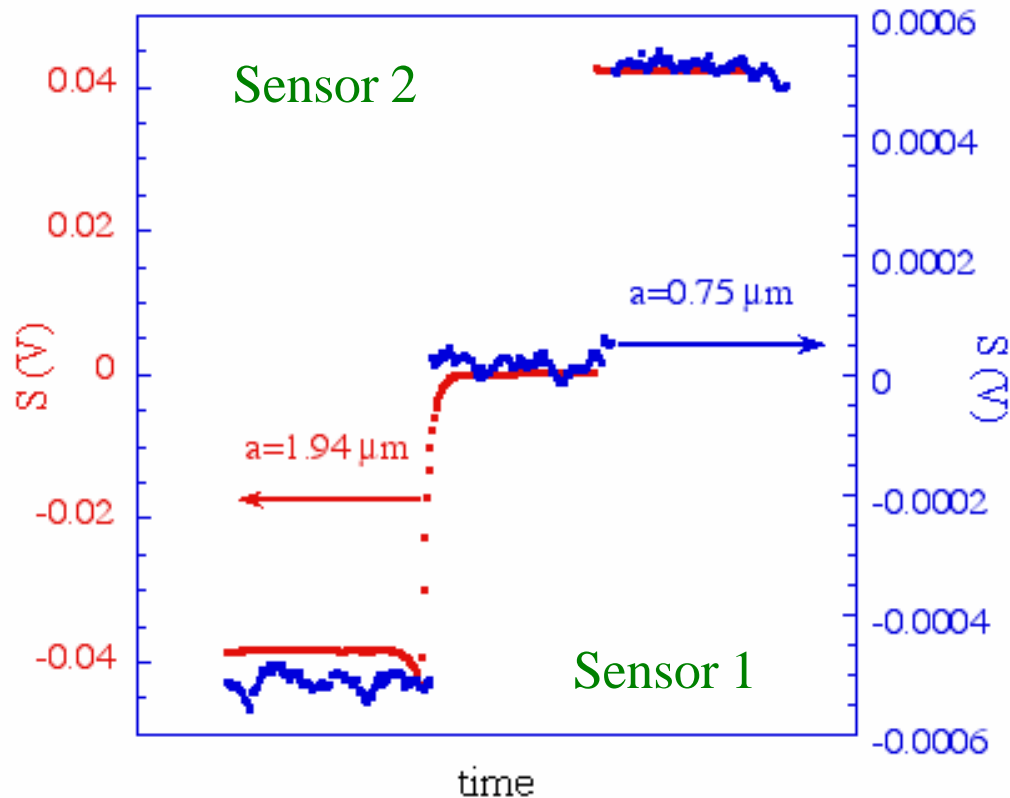
M. Miller

Localized magnetization “scissoring”

- Absent a bead, sensor is decoupled from applied H_z
 - Bead induces a small perturbation to total resistance of sensor
 - $DR \sim \text{number of beads}$
- Dynamic range x100
(sense 10 to 1000 beads)



Example of BARC detection

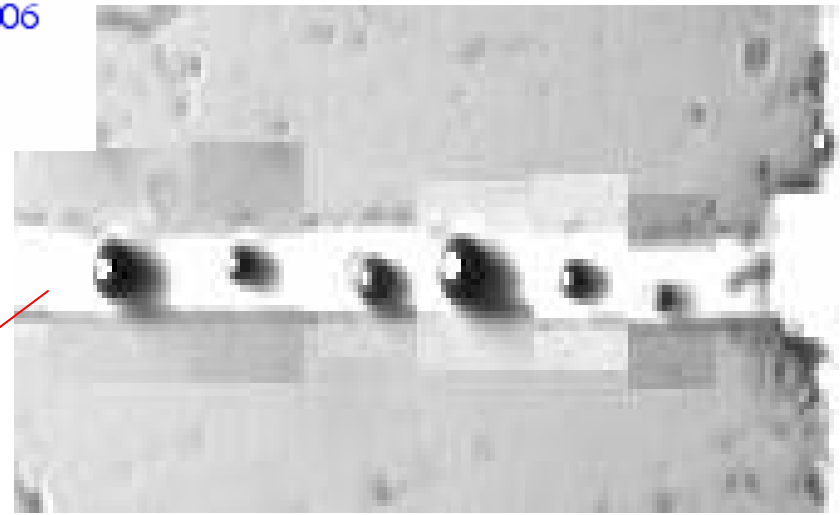


- **0.75** and **2.0 μm** Py beads
- **Sensor 2** not shown (bridge geometry)
- Move beads between Sensors 1 and 2
- Bigger signal for bigger beads!

1. *Biosensors & Bioelectronics* **13**, 731-739 (1998)
2. *Biosensors & Bioelectronics* **14**, 805-739 (2000)
3. *J.Mag.Mag.Mat.* **225**, 138-144 (2001)

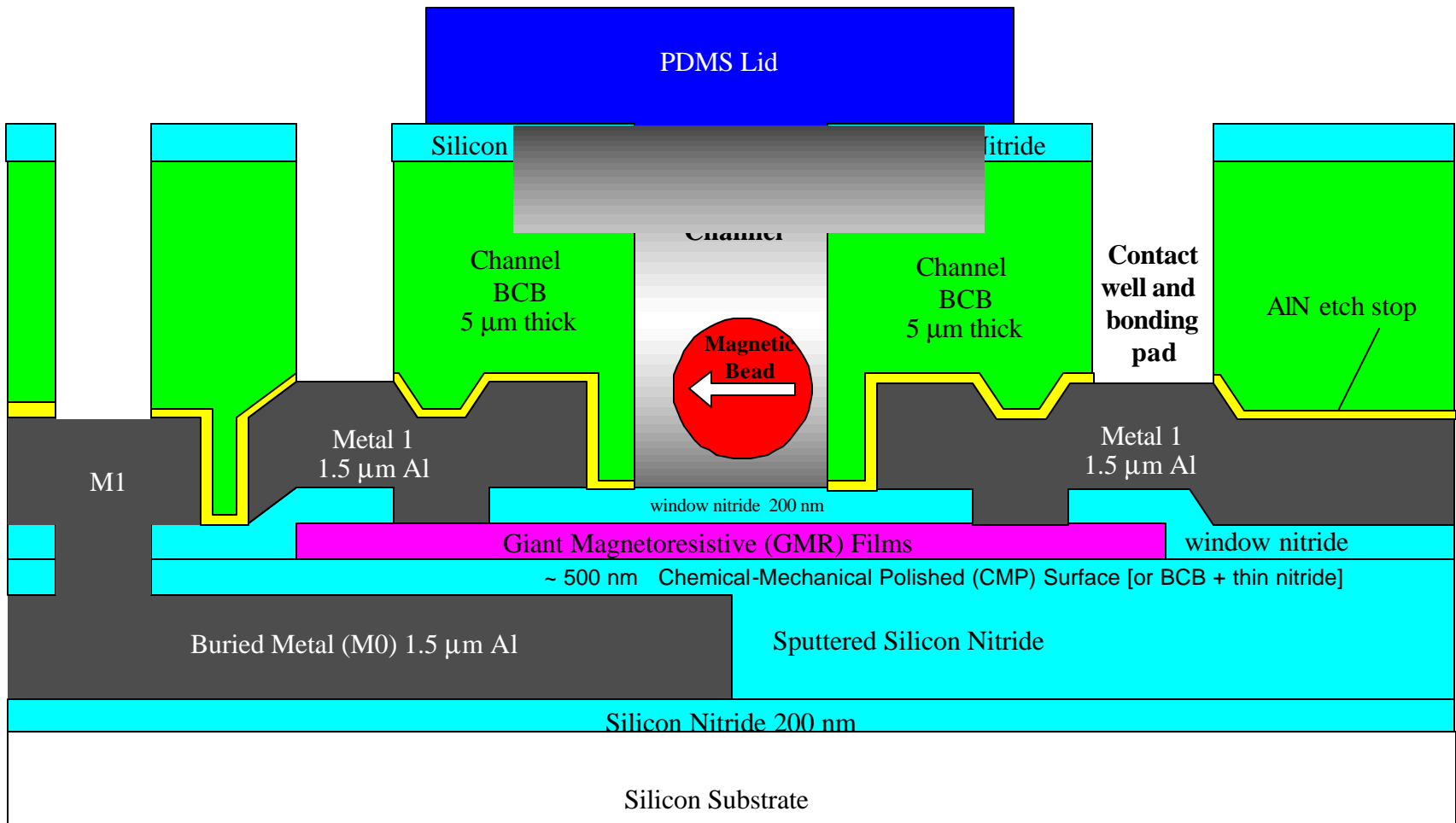
M. Miller

Sensor 1

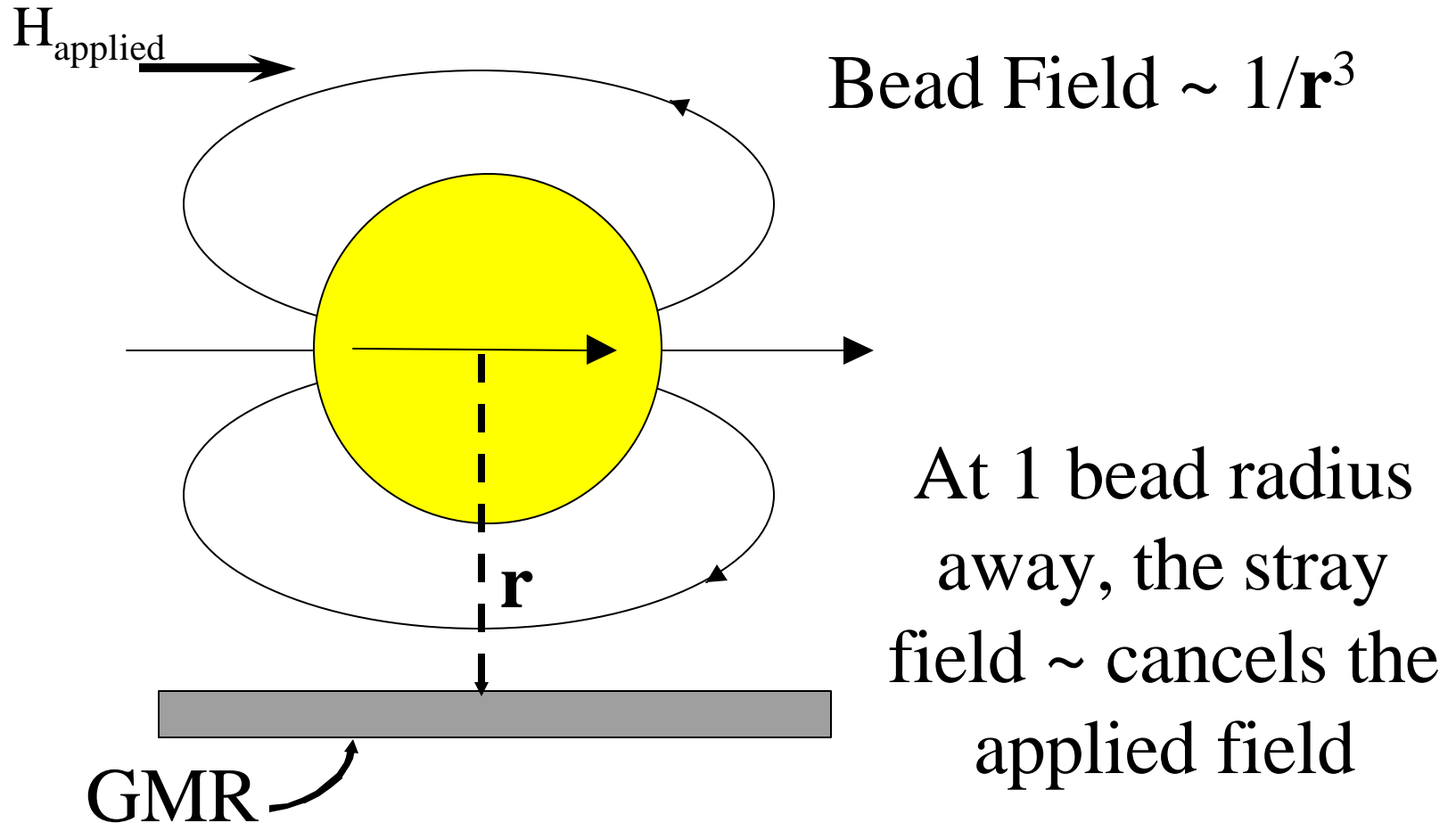


GMR / Fluidics Process Cross Section

Integration of fluidics and sensing



Stray Fields from Magnetic Beads

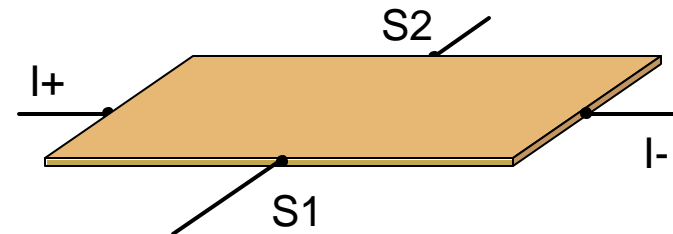
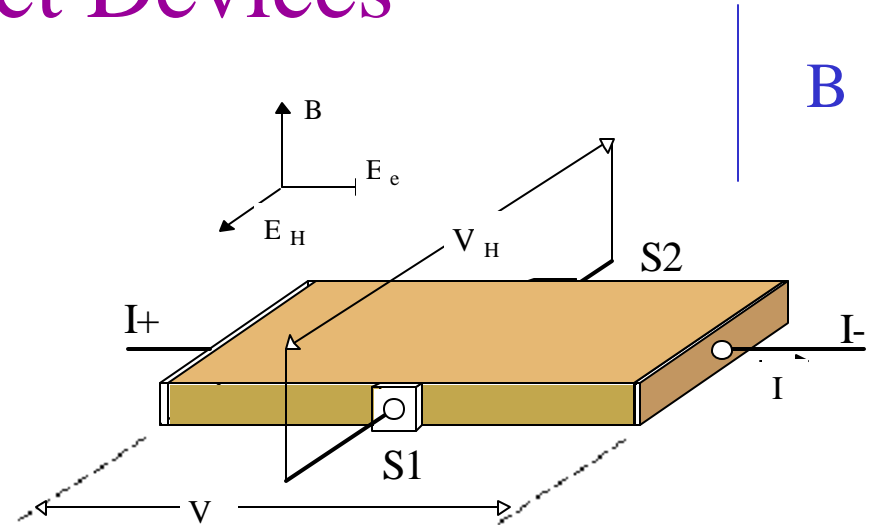


MR sensors (magnetic tunnel junctions and spin valves)

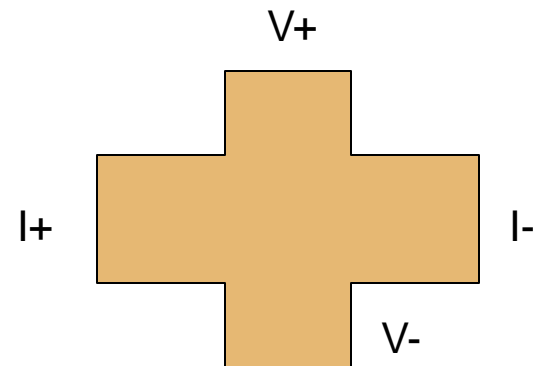
- Sensor technology (individual sensors) mature
 - Concern about scaling and micromagnetism
- Memory array technology (arrays of many sensors) still in “research and development”
- Many players
 - Mark Tondra (NVE)
 - Jagadeesh Moodera (MIT, Bitter Magnet Lab)
 - Gang Xiao (Brown)
 - Shan Wang (Stanford)

Hall Effect Devices

- Sensitive to perpendicular fields, B_Z
- Classical Lorentz force, $\mathbf{v} \times \mathbf{B}$
- $(V_H / I) = (R_H / t) B_Z$
- $R_H \propto 1/n$ (n =density of carriers)
- Sensitivity for high mobility heterostructures (InAs):
0.5 Ω/Oe
- Good scaling

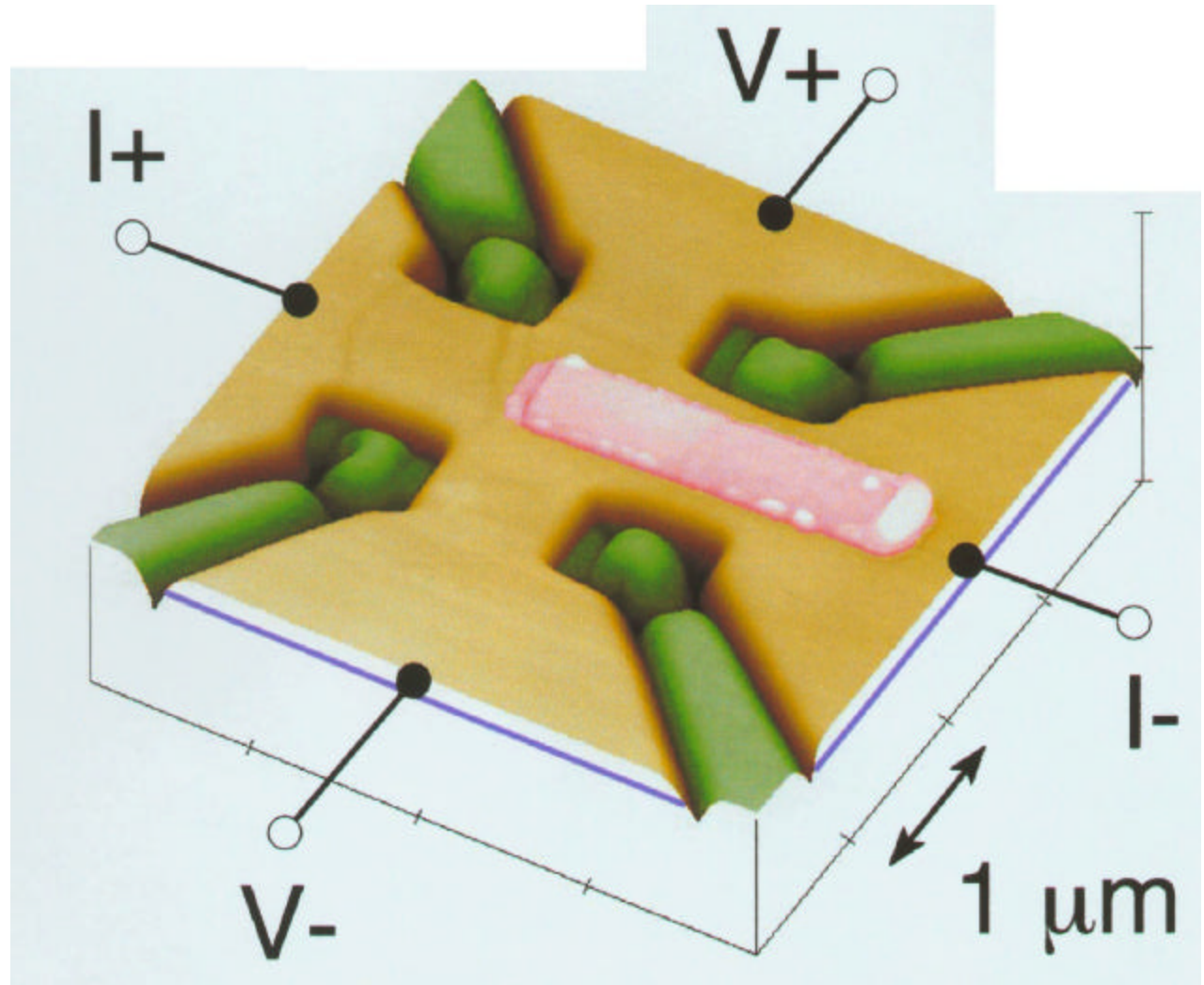


TOP VIEW
Schematic,
Patterned
device



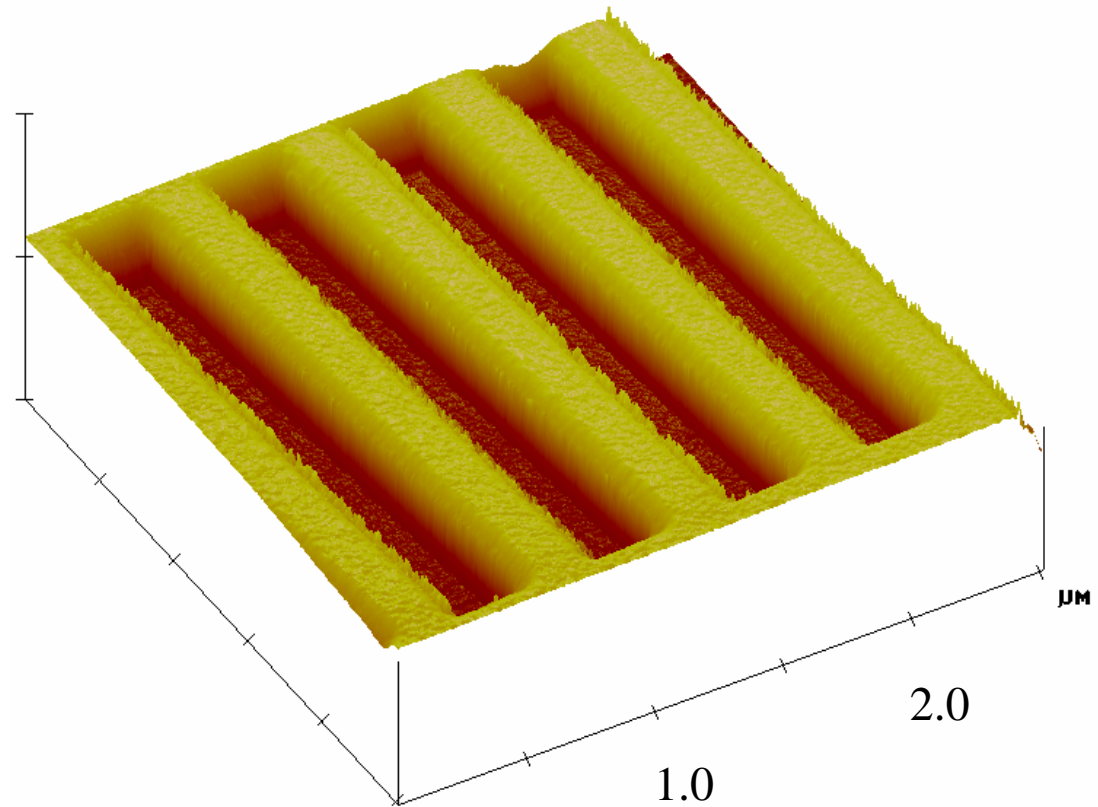
Hall cross fabricated by FIB

- Example of Hall device developed for nonvolatile memory
- False colored AFM image
- Hall plate is InAs single quantum well
- $f = 500$ nm



Developing e-beam lithography for nm scale Hall sensors

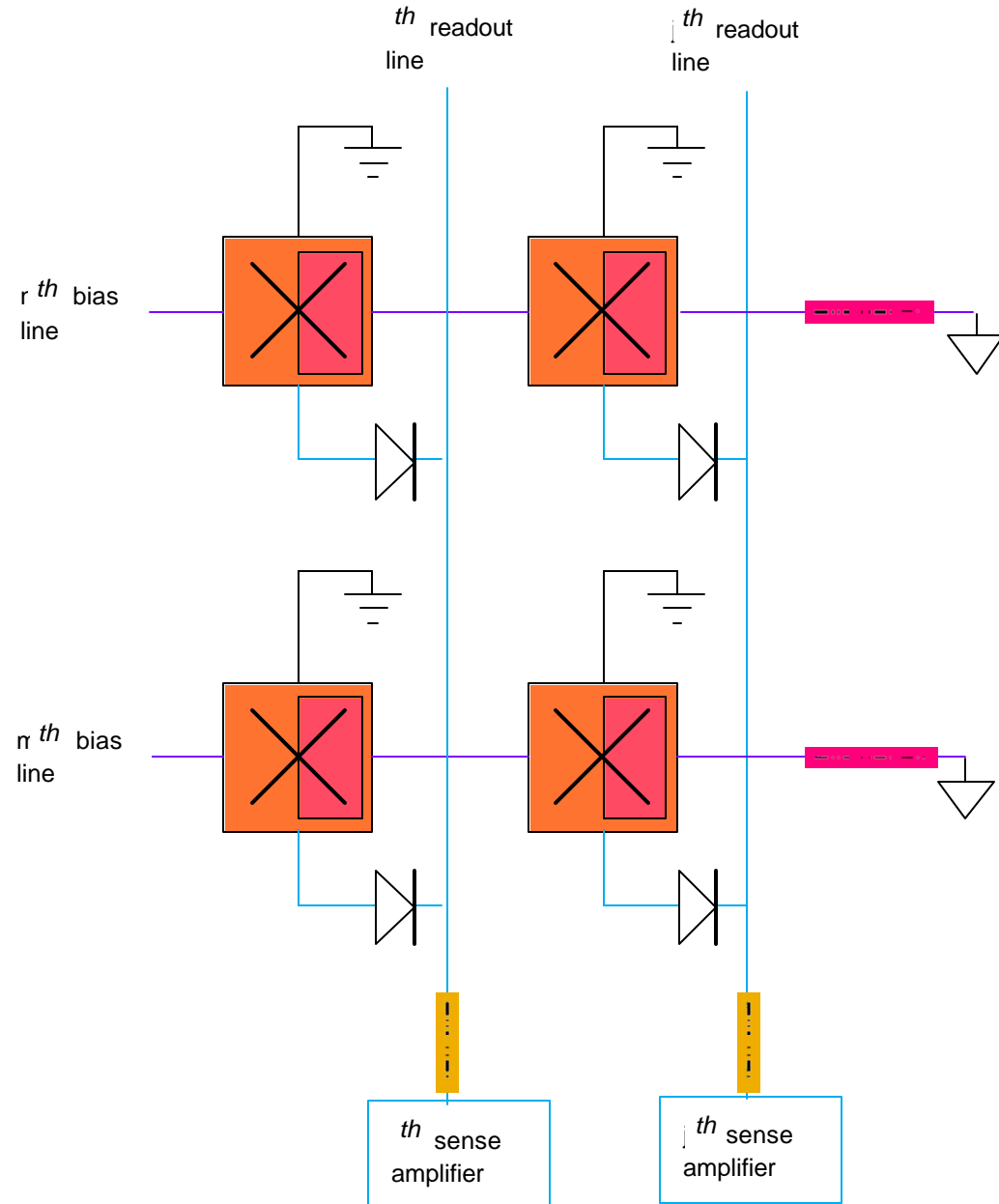
- Grating test structure, EBL and ion mill
- My approach:
 - Develop individual prototypes that are very sensitive
 - Optimize other characteristics for given need
 - Develop architecture (series or 2-dim arrays, etc.) for particular need



Memory Arrays

Sensor Arrays

- 2-dim array of memory cells, bit addressable
- Need isolation element in each cell
- Same architecture can be used for sensors, each cell is a “magnetic pixel”
- High sensitivity
- Relatively high circuit complexity



Summary

- Integrated sensors for localized magnetic fields
 - Magnetic tunnel junctions, spin valves, Hall effect
- Properties for consideration:
 - Sensitivity to relevant component of field (ideally, sense all components)
 - Insensitivity to externally applied field
 - Sensing at dc (rather than ac, lockin techniques) offers greatest flexibility
 - $dR/dB \big|_{B=0}$ large
 - Sensor should be close to surface
 - Surface should permit functionalization
 - Variety of architectures (meander line, 2-dim arrays)
 - Scalability: maintain sensitivity as f shrinks
 - Si (CMOS, SOI) or GaAs compatible